

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION: **MARCHAND, Gilles**

GROUP ART UNIT: TBA

SERIAL NUMBER: 10/576,345

EXAMINER: TBA

FILED: April 18, 2006

**FOR: OPERATING DEVICE COMPRISING A LOCALIZED ZONE FOR THE CAPTURE OF
A DROP OF A LIQUID OF INTEREST**

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. 1.97

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicant(s) wish to disclose the following information.

REFERENCES

- ☒ The Applicant(s) wish to make of record the references listed on the attached PTO/ SB/08. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- ☐ A check is attached in the amount required under 37 CFR § 1.17(p).

RELATED CASES

- ☐ Attached is a list of applicant's pending applications or issued patents which may be related to the present application. A copy of the patent(s) is attached along with PTO/ SB/08.
- ☐ A check is attached in the amount required under 37 CFR § 1.17(p).

CERTIFICATION

The undersigned certifies that

- ☐ each item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☐ no item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR § 1.56(c) more than three months prior to the filing of this statement.

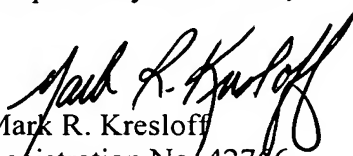
PETITION

- ☐ Applicant(s) hereby request consideration of the attached information. A check is attached in the amount of the Petition fee required under 37 CFR § 1.17(i)(1).

DEPOSIT ACCOUNT

- Please charge any additional fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit account No. 50-0911. A duplicate copy of this sheet is enclosed.

Respectfully submitted,



Mark R. Kresloff
Registration No. 42766
MCKENNA LONG & ALDRIDGE LLP
1900 K Street, N.W.
Washington, D.C. 20006
Telephone No: (202) 496-7500
Date: October 23, 2006

Substitute for form 1449/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Complete if Known	
				Application Number	10/576,345
				Filing Date	April 18, 2006
				First Named Inventor	MARCHAND, Gilles
				Art Unit	TBA
				Examiner Name	TBA
Sheet	1	of	1	Attorney Docket Number	10404.039.00-US

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
	AA	6,565,813 B1	05-20-2003	Garyantes	
	AB	6,210,894 B1	04-03-2001	Brennan	
	AC	6,143,496	11-07-2000	Brown et al.	
	AD	6,040,193	03-21-2000	Affymetrix Inc	

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
	BA	WO 03/059518 A1	07-24-2003	University College Cork- National University of Ireland, Cork		
	BB	WO 01/87458 A1	11-22-2001	University of Cincinnati		
	BC	WO 02/41992 A2	05-30-2002	Siemens Aktiengesellschaft		
	BD	WO 02/16023 A2	02-28-2002	Proto-Gene Laboratories, Inc.		
	BE	WO 99/03684	01-28-1999	Cambridge Sensors Limited		
	BF	WO 0036145	06-22-2000	Commissariat Energie Atomique		
	BG	WO 02/090573 A2	11-14-2002	Infineon Technologies AG		
	BH	EP 0 561 722 A1	03-17-1993	Bio Merieux		
	BI	FR 2 818 662 A1	12-22-2000	Commissariat Energie Atomique		

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the application number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

NON PATENT LITERATURE DOCUMENTS					
Examiner Initials [*]	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			T ²
	CA	Azek, F., et al., <i>Hybridization Assay at a Disposal Electrochemical Biosensor for the Attomole Detection of Amplified Human Cytomegalovirus DNA</i> , Analytical Biochemistry, 284, pp. 107-113			
	CB	Lee, J., et al., <i>Electrowetting and electrowetting-on-dielectric for microscale liquid handling</i> , Elsevier, Dept. of Mechanical Engineering, Northwestern University, pp. 259-268			
	CC	Bratten, C., et al., <i>Micromachining Sensors for Electrochemical Measurement in Subnanoliter Volumes</i> , Analytical Chemistry, Vol. 69, 1997, pp. 253-258			
	CD	Yang, Mengsu, et al., <i>Covalent Immobilization of Oligonucleotides on Modified Glass/Silicon Surfaces for Solid-phase DNA Hybridization and Amplification</i> , The Chemical Society of Japan, 1998, pp. 257-258			
	CE	Boncheva, M., et al., <i>Design of Oligonucleotide Arrays at Interfaces</i> , American Chemical Society, 1999, pp. 4317-4320			
	CF	Jansen, H., et al., <i>The black silicon method: a universal method for determining the parameter setting of a fluorine-based reactive ion etcher in deep silicon trench etching with profile control</i> , MESA Research Institute, University of Twente, 1995, pp. 115-120			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

Examiner Signature		Date Considered	
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